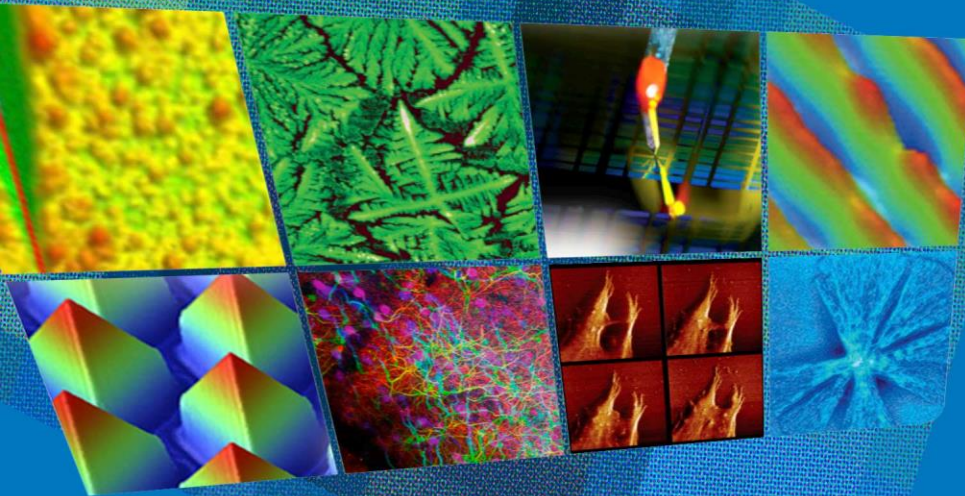
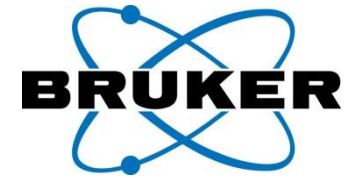


Solving Challenges in Defect Inspection of Advanced Optics



Atomic Force Microscopy
3D Optical Microscopy
Fluorescence Microscopy
Tribology
Stylus Profilometry
Nanoindentation

Welcome to the Webinar



- For best audio experience, everyone is on mute



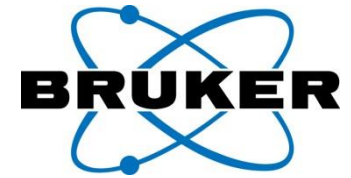
- For questions, use the Chat



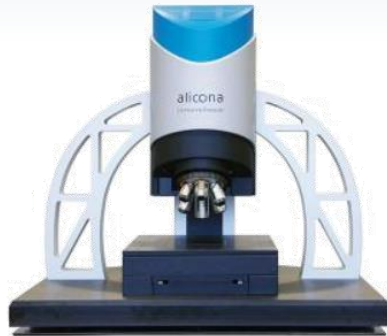
- Questions will be answered at end of webinar
- Webinar is recorded and will be available offline
 - Feel free to share and forward to colleagues

Foreword

Bruker Nano Surfaces division



3D Optical Microscopy WLI & Focus Variation



Atomic Force Microscopy



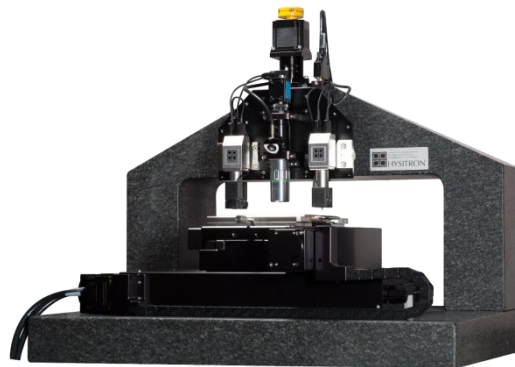
Stylus Profilometry

Bruker Nano Surfaces Division

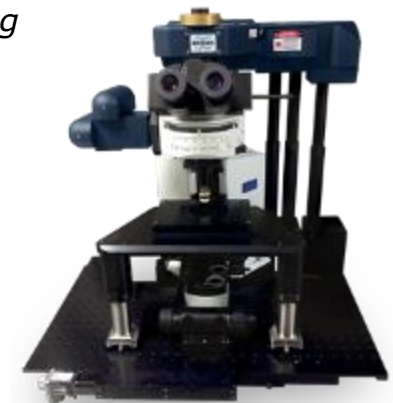
Pioneers in Microscopy, Metrology & Mechanical Testing



Universal Mechanical Testing and Tribology



Hysitron Nanomechanical Testing



Multiphoton & Super-Resolution Fluorescence Microscopy



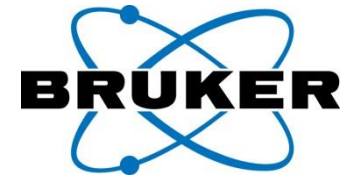
- Quality control of high-end optics
 - On surface
 - Beyond classical visual inspection
- Solutions through direct measurement of topography
 - Non-contact profiler based on interferometry
- Information on automation and data processing
 - Strategy to detect defects on complex shapes
 - Strategy to measure large and aspheric optics
 - Final defect map



Background

Fine Optics for Advanced Applications

Defect review



Inertial detection system / gyrolaser

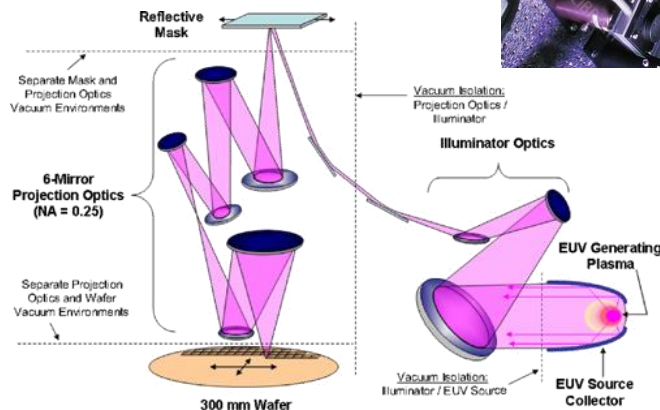


High Laser power Optics

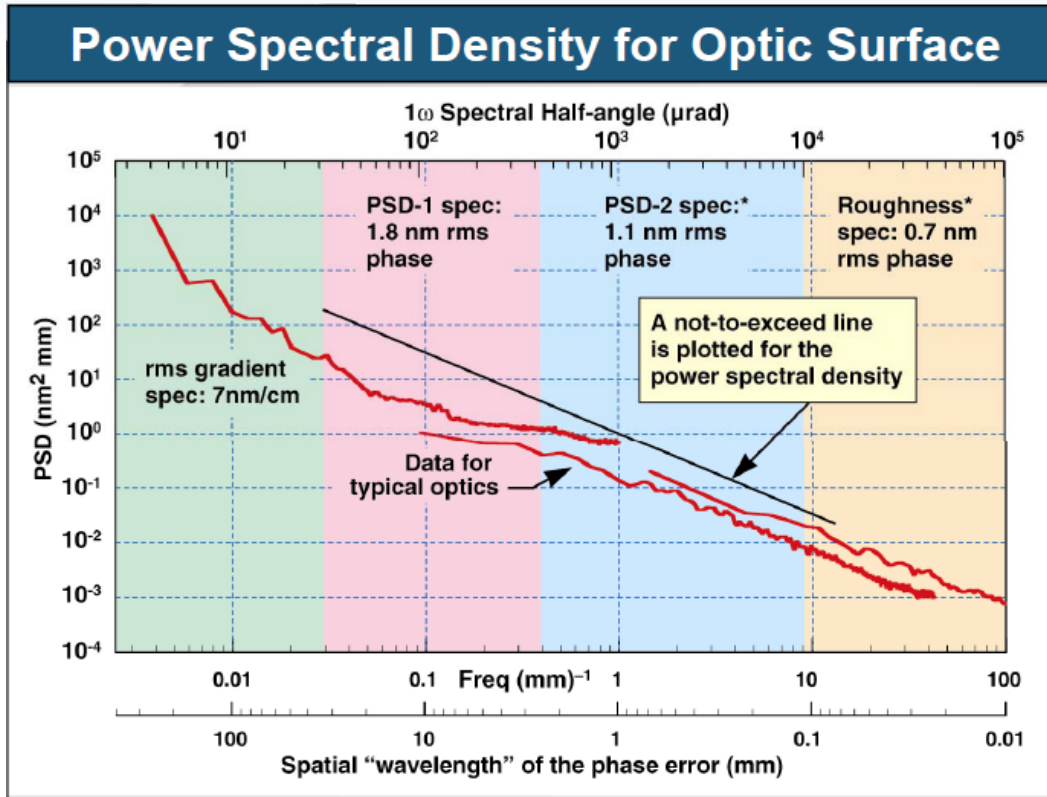
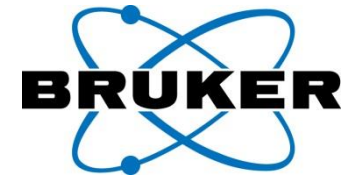


- Usually smaller optics
 - Size below 100x100x80 mm³
- Performances of optics are critical
 - High-quality focus
 - Zero defect
 - 100% inspection
 - Manual and/or high-end polishing
- Defects cause:
 - Spurious diffraction/loss of function
 - Issue in assembly
- Defects can only be detected through topography measurement

eUV litho system



Metrics for High-Quality Optics



High Level Requirements¹

Surface

Peak-to-Valley	211 nm ($\lambda/3$)
Gradient	<7 nm/cm
PSD1	1.8 nm
PSD2	1.1 nm
Roughness	4-10 Ang
Scratch/Dig ²	20/10

Sub-nm roughness
Lateral resolution $\sim 1 \mu\text{m}$

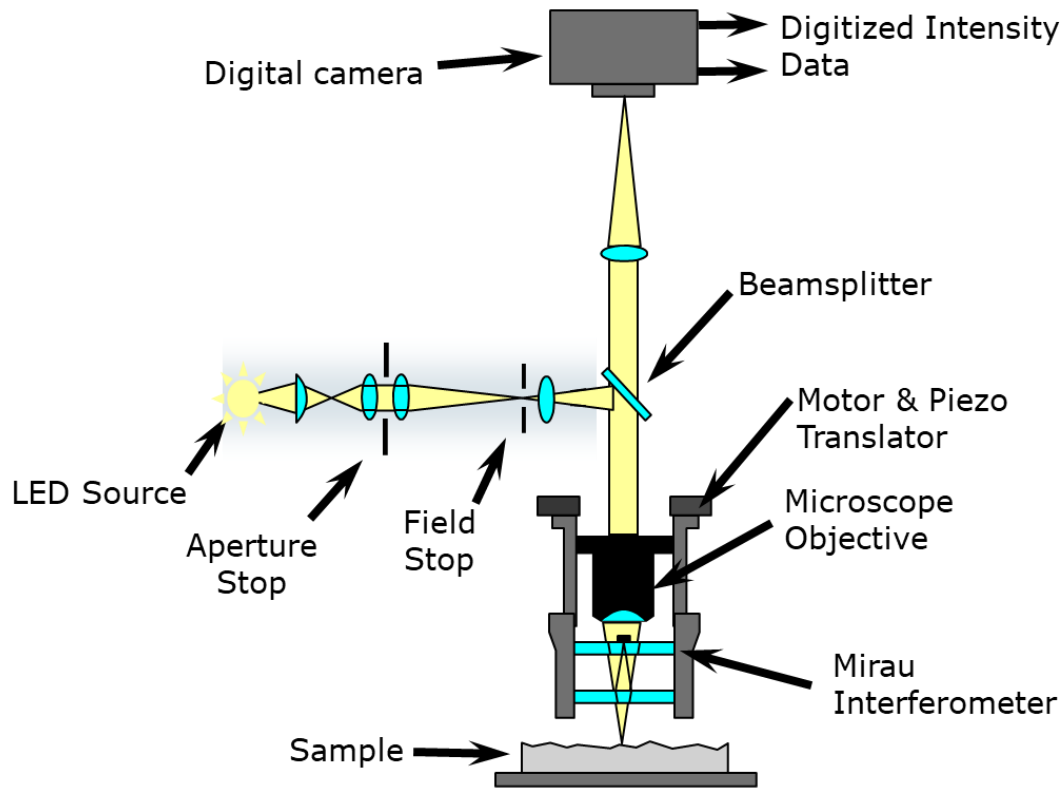
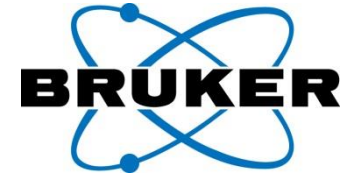
From Glass Processing Course (Lehigh University; Spring 2015)
Tayyab Suratwala, Lawrence Livermore National Laboratory



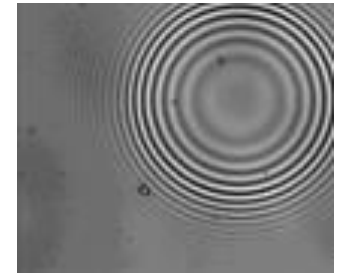
Non-Contact Interferometric Profiler

Non-Contact Interferometric Profiler

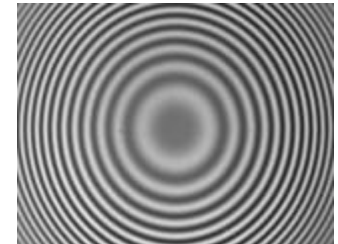
Key components



Broad white illumination

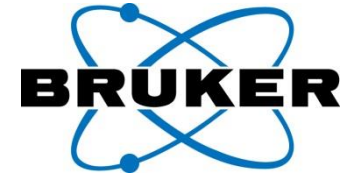


Monochromatic illumination

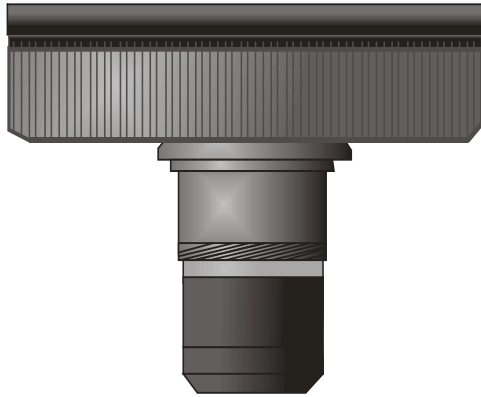


Non-Contact Interferometric Profiler

Core modes to get topography



Motor scanning

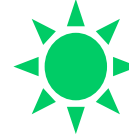


Broad white illumination

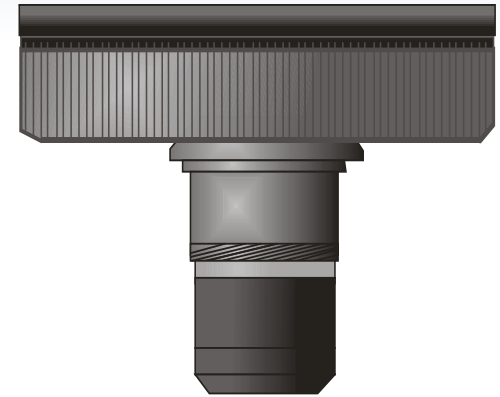


Vertical Scanning Interferometry

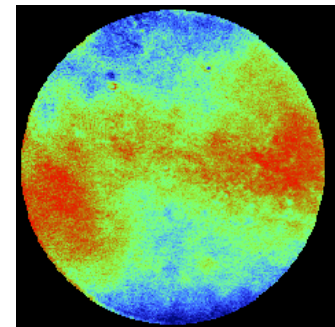
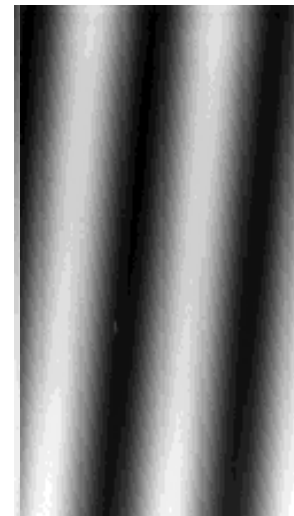
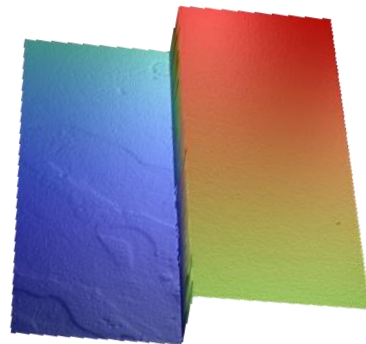
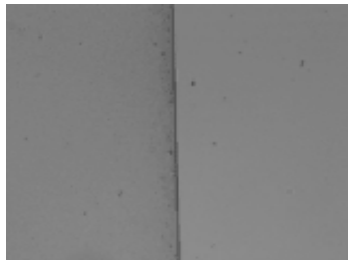
Monochromatic illumination



Phase Shifting Interferometry

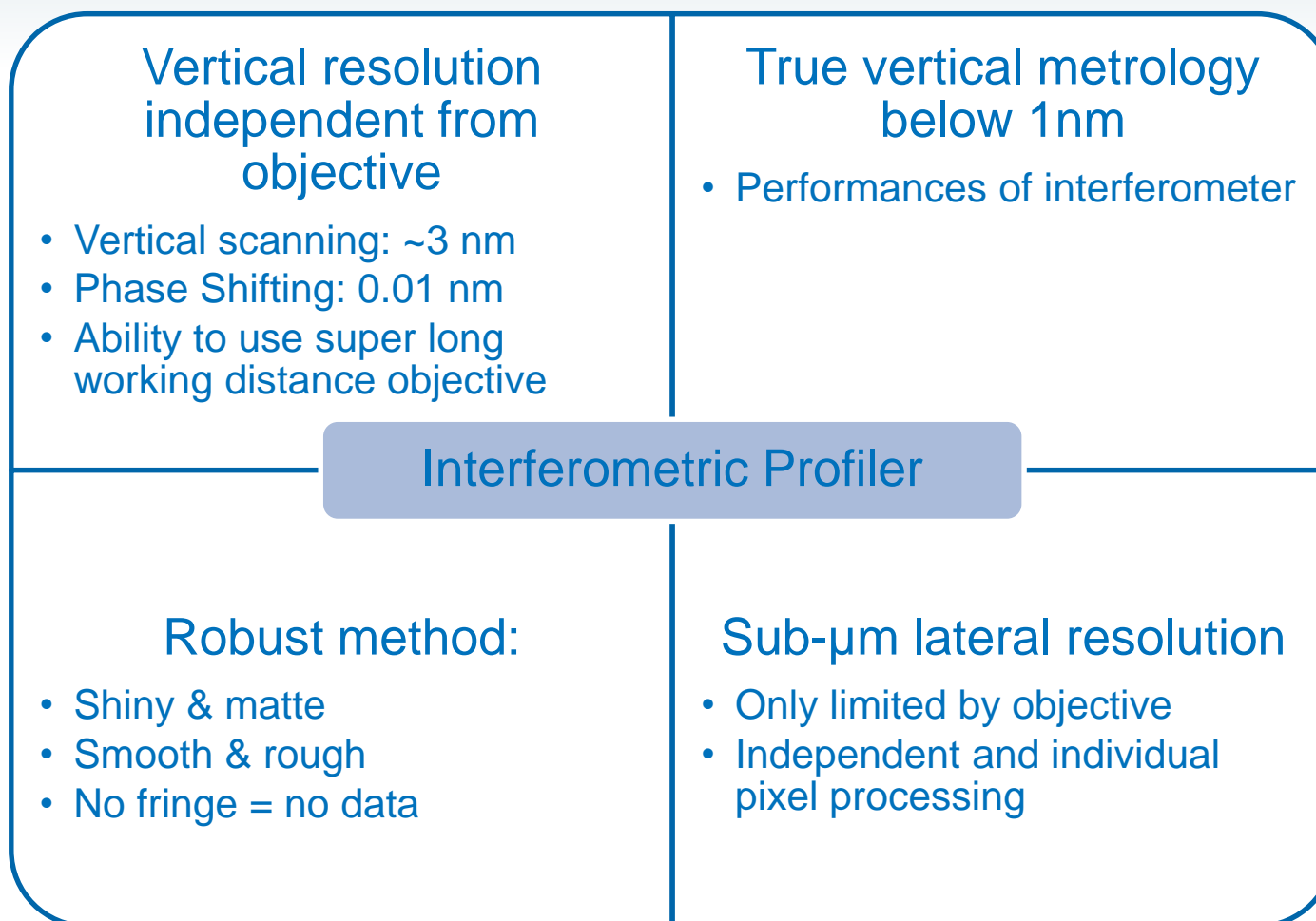


Piezo scanning



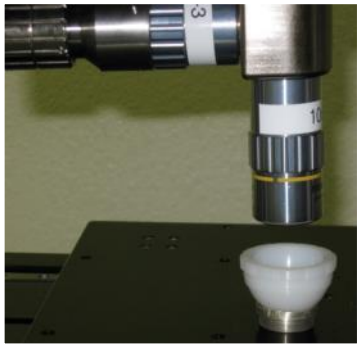
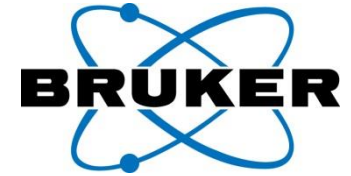
Non-Contact Interferometric Profiler

Core attributes

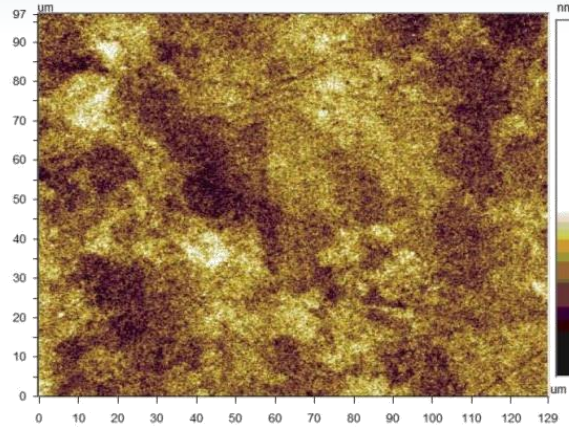


Non-Contact Interferometric Profiler

Core attributes - illustration

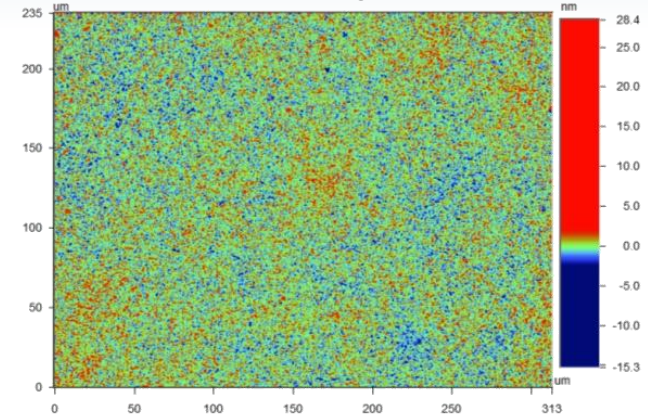


Mirror (90% reflectivity)

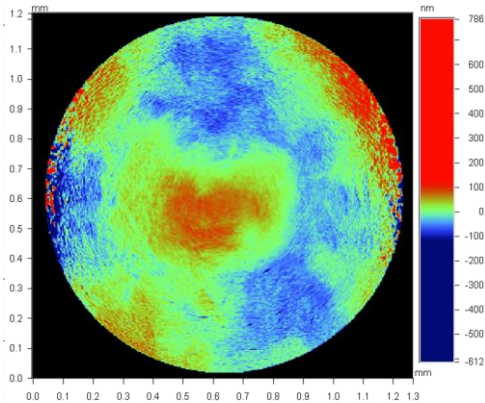


$Sa=0.07 \text{ nm}$

Anti-reflective coating (0.4% reflectivity)

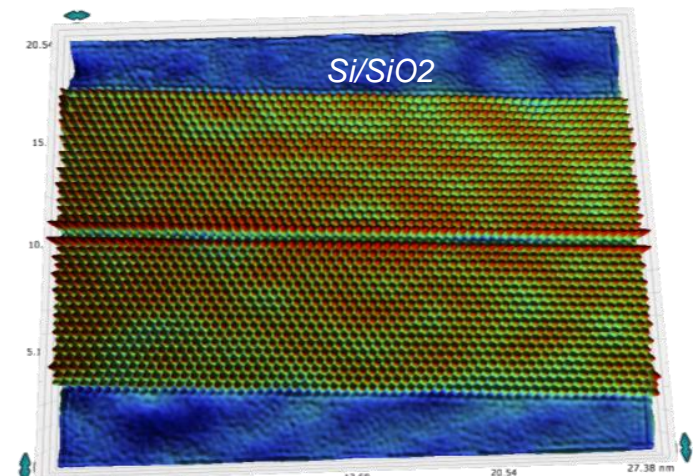


$Sa=0.75 \text{ nm}$



$Sa=28 \text{ nm}$

190 nm diameter pillars
spaced by 900 nm

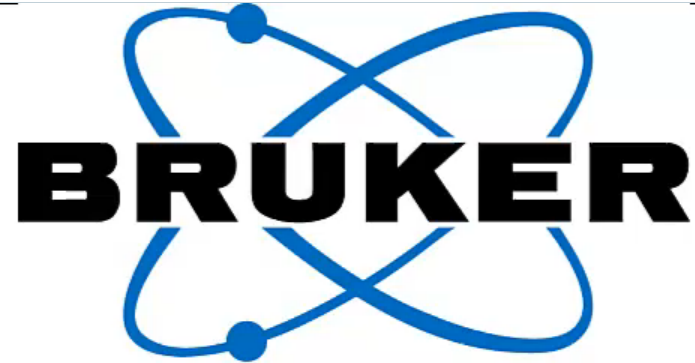
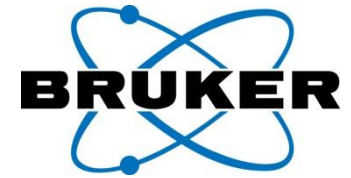


Solutions for quality control

1. Power Spectrum Density

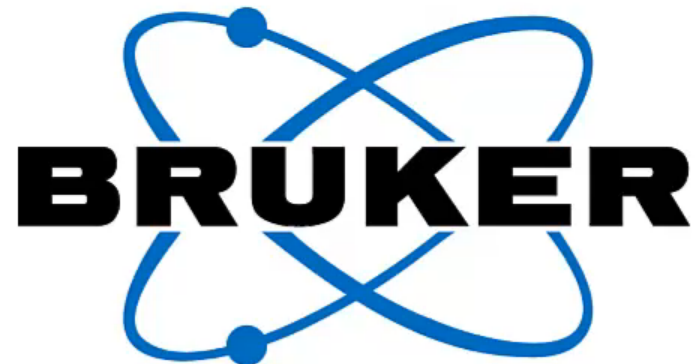
Power Spectrum Density

Automatic acquisition

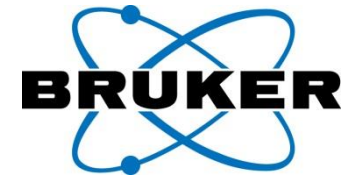


[View Video](#)

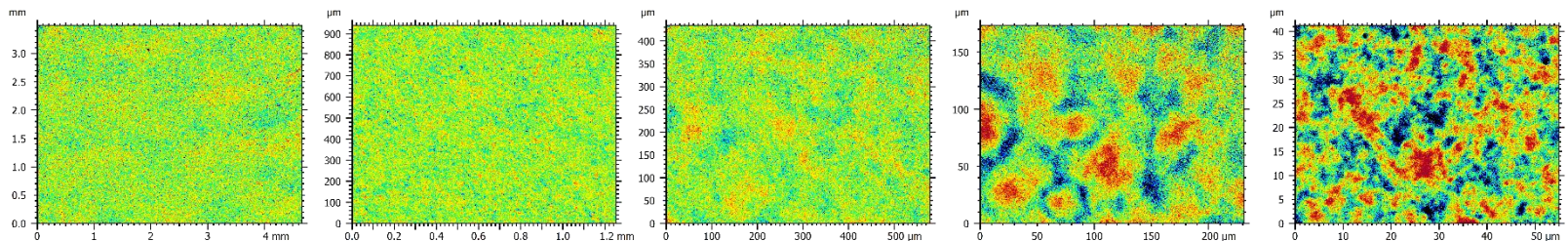
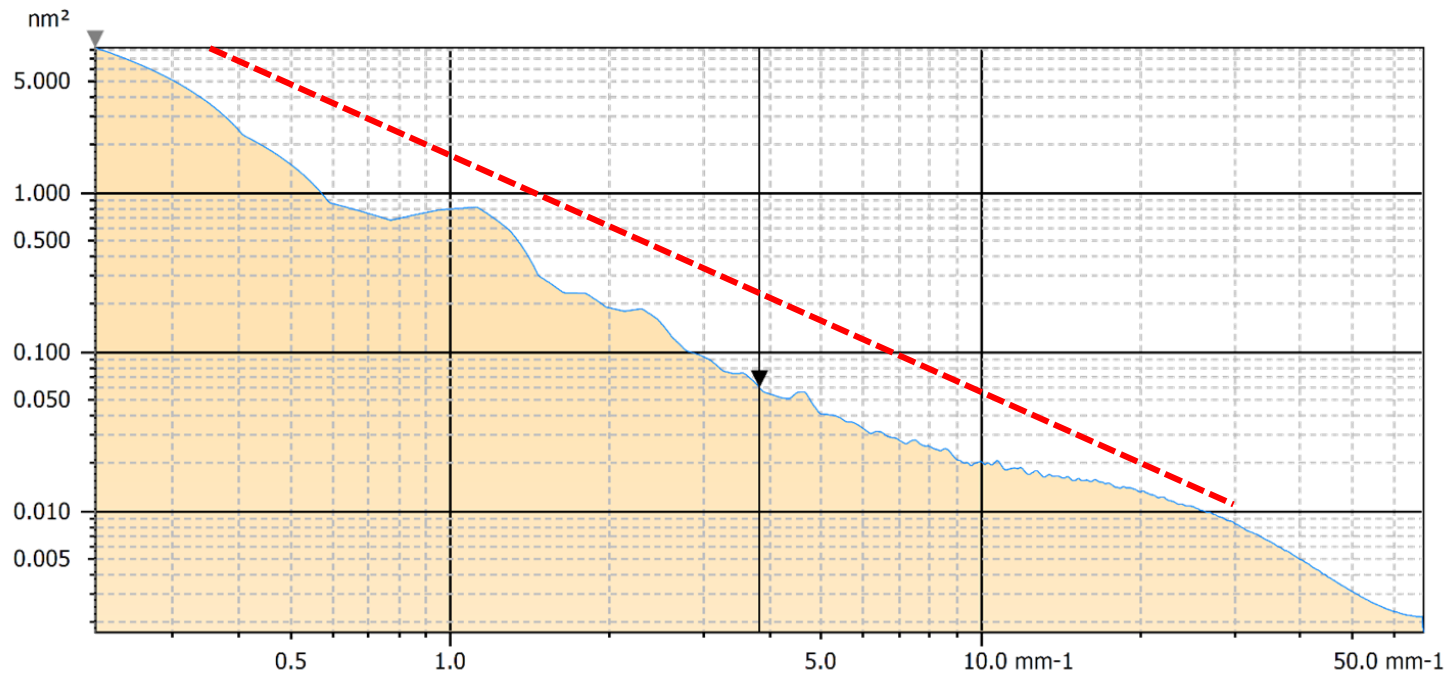
Automatic collection of full range
Power Spectrum Density



Power Spectrum Density Single graph representation



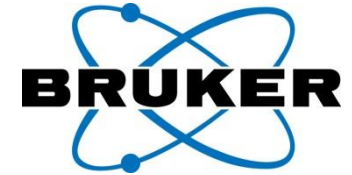
Averaged power spectrum density (PSD)



Vertical scale
 $\pm 0.5 \text{ nm}$
Form removed

2. Automatic inspection

Quality Control Defect review



Inertial detection system / gyrolaser

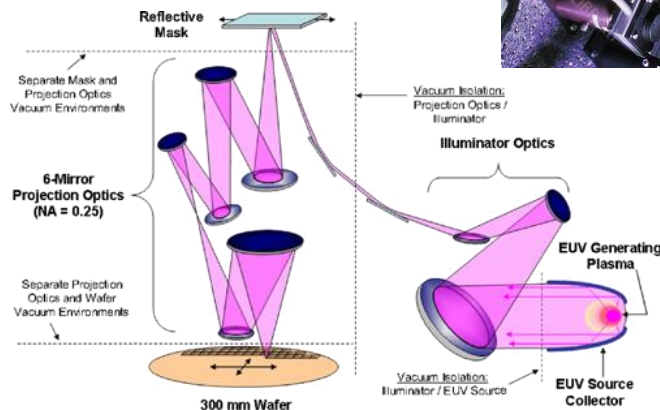


High laser power optics



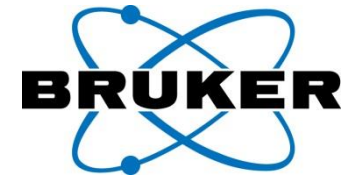
- Current solutions are time and user consuming
 - Manual inspection by operator
 - Normaski microscope
 - Inconsistency
 - User dependent
 - No vertical metrology
- Proposed solution
 - Full automation
 - Unattended operation
 - Complete metrology
 - Robust versus all situations

eUV litho system

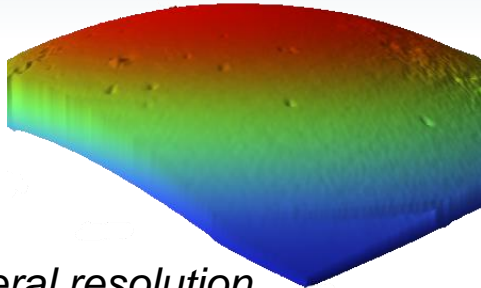


Quality Control

Advanced mode to get topography



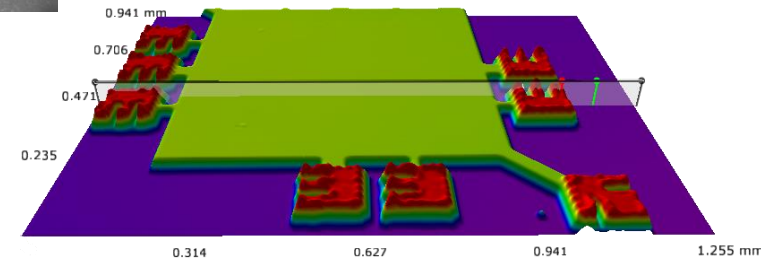
Steady and smooth slopes



Large field of view

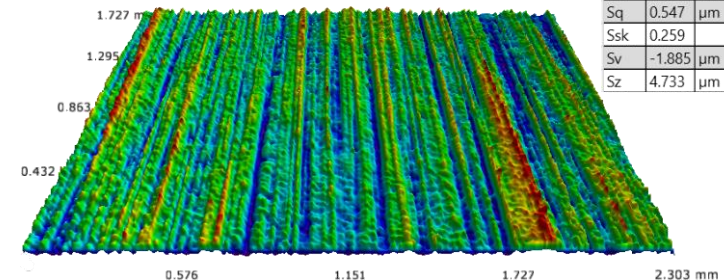
R:	M:	1714.207 nm
X:0.546	X:0.587	
Y:0.224	Y:0.224	
Z:0.646	Z:0.013	

-8.023 nm
dx=80.286 um, dz=-1.378 um, Slope=-0.017



Accurate stepped surface

Sa	0.44	μm
Sku	2.857	
Sp	2.848	μm
Sq	0.547	μm
Ssk	0.259	
Sv	-1.885	μm
Sz	4.733	μm

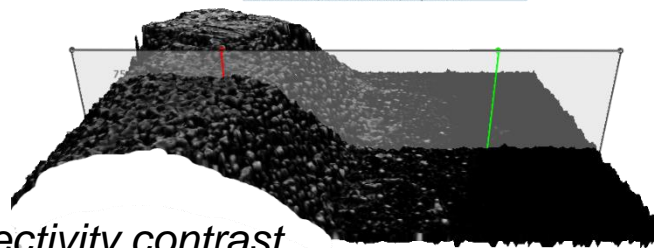


Accurate sub-μm roughness

**Self-adapting mode
combining Phase
Shifting and Vertical
Scanning modes**

R:	M:	22047.956 nm
X:0.175	X:0.498	
Y:0.192	Y:0.192	
Z:0.767	Z:0.094	

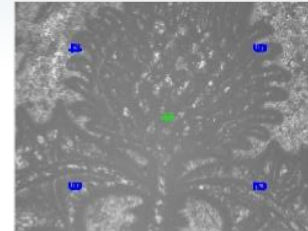
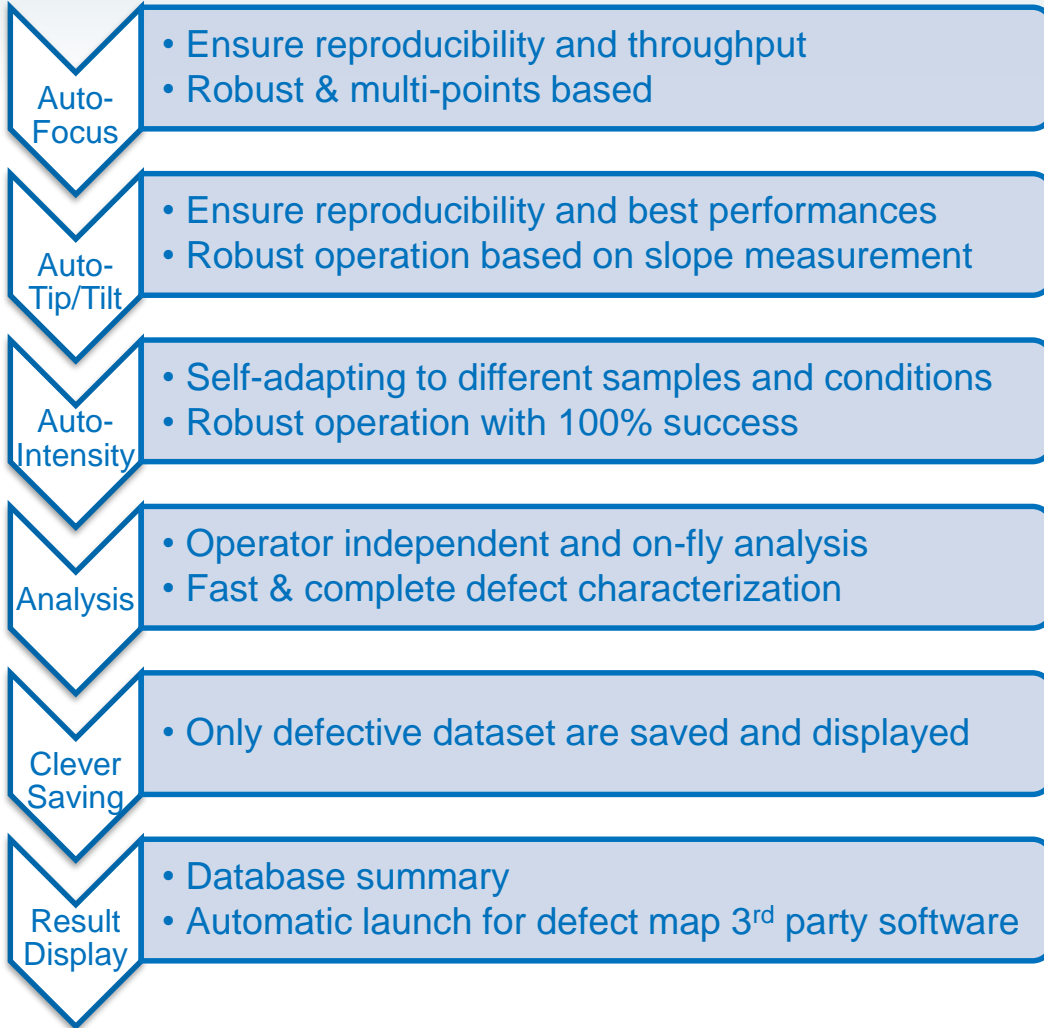
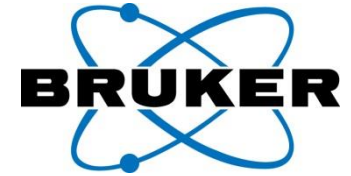
-555.397 nm
dx=50.895 um, dz=-20.564 um, Slope=-0.404



High-reflectivity contrast

Quality Control

Need for 100% automation



Run Time Options

- Retry with Coarse Autofocus if Fine Autofocus fails
- Cycle through all Autofocus locations until successful
- Prompt for manual focus upon failure

Views

Results Gallery

Display

Saving

- Save Failed Data

File Name:

Post Sequence

- Move To Z Safe
- Unload XY Stage
- Unload Theta

External Program:

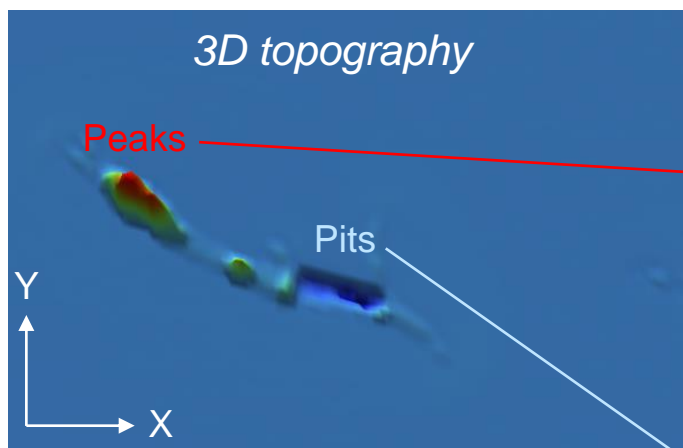
- Run External Program
-

Command Line Argument:

- Wait For Program To Exit

Full Characterization of Defects

Direct saving of all parameters



No	Region	A Diameter μm	Rp% μm	X Diameter μm	Y Diameter μm
1		17.129	1.35	29.335	14.667
2		6.143	0.75	6.845	3.911
3		5.838	0.23	3.911	6.845

Output File

Log File: C:\ProgramData\Bruker\Vision\Data\Defects\Peak_Defects.csv

Output File Format

Multiple Region Default Vision Database Compatible

Options

Include Time Stamp Include Header Include Summary

Direct and automatic export of whole tab into CSV file

- A Diameter: mean diameter derived from defect area
- X & Y Diameters: length and width along X & Y directions
- Rp%: highest point for peak defect
- Rv%: deepest point for pit defect

No	Region	A Diameter μm	Rv% μm	X Diameter μm	Y Diameter μm
1		12.385	-0.50	25.423	4.889

Output File

Log File: C:\ProgramData\Bruker\Vision\Data\Defects\Pit_Defects.csv

Output File Format

Multiple Region Default Vision Database Compatible

Options

Include Time Stamp Include Header Include Summary

Direct Recording of Results

Custom CSV file



No	Region	A Diameter μm	Rp% μm	X Diameter μm	Y Diameter μm
1		17.129	1.35	29.335	14.667
2		6.143	0.75	6.845	3.911
3		5.838	0.23	3.911	6.845

No	Region	A Diameter μm	Rv% μm	X Diameter μm	Y Diameter μm
1		12.385	-0.50	25.423	4.889

Life database update

Database

Measurement Number	Time	Row	Column	Islands	Max A Diameter μm	Max Rp% μm	Max X Diameter μm	Max Y Diameter μm	Islands	Max A Diameter μm	Max Rv% μm	Max X Diameter μm	Max Y Diameter μm
1	7:30:49 PM	2	16	3	17.129	1.354	29.335	14.667	1	12.385	-502.628	25.423	4.889

(1,1)	(1,2)	(1,3)	(1,4)	(1,5)	(1,6)	(1,7)	(1,8)
(2,1)	(2,2)	(2,3)	(2,4)	(2,5)	(2,6)	(2,7)	(2,8)
(3,1)	(3,2)	(3,3)	(3,4)	(3,5)	(3,6)	(3,7)	(3,8)
(4,1)	(4,2)	(4,3)	(4,4)	(4,5)	(4,6)	(4,7)	(4,8)
(5,1)	(5,2)	(5,3)	(5,4)	(5,5)	(5,6)	(5,7)	(5,8)
(6,1)	(6,2)	(6,3)	(6,4)	(6,5)	(6,6)	(6,7)	(6,8)
(7,1)	(7,2)	(7,3)	(7,4)	(7,5)	(7,6)	(7,7)	(7,8)
(8,1)	(8,2)	(8,3)	(8,4)	(8,5)	(8,6)	(8,7)	(8,8)

Summary for peaks:

1. Number of detected peaks
2. Maximum average diameter
3. Maximum length of peak along XY directions

Summary for pits:

1. Number of detected pits
2. Maximum average diameter
3. Maximum length of pit along XY directions

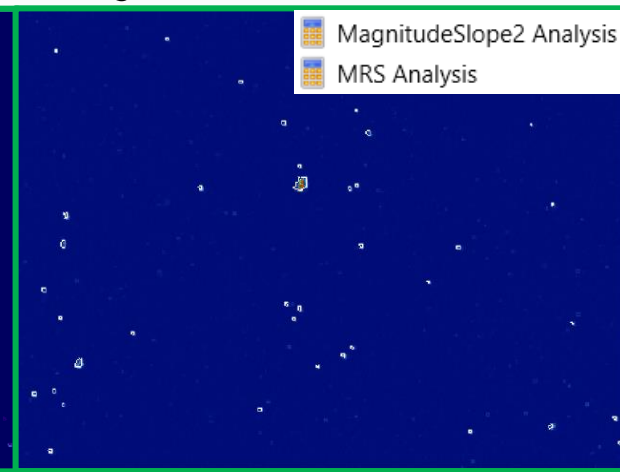
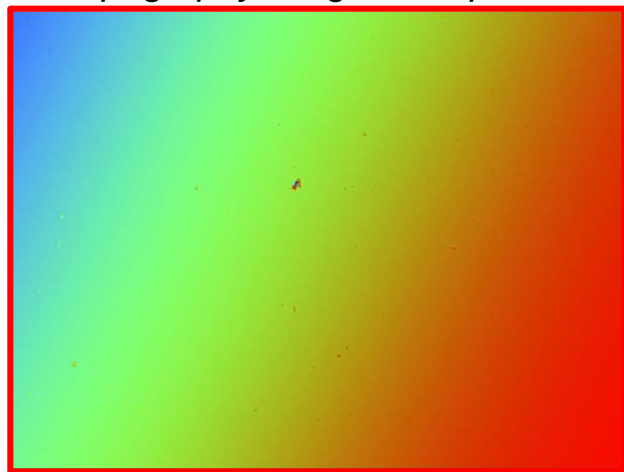
Defect Detection by Slope

Higher throughput and more robust



Topography image on aspheric

Derivative image

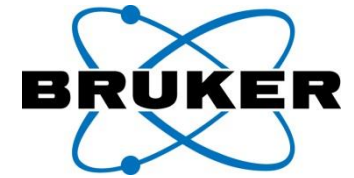


- Automatic analysis based on slope variation
- Robust and efficient way to spot defects:
 - Faster processing: directly from Raw image
 - Irrespective of shape/form/local slope
 - Robust versus noise or vibrations
- Multiple region analysis to get data on each defect

No	Region	A Diameter µm	X Diameter µm	Y Diameter µm
19		13.692	13.690	14.667
10		8.183	6.845	8.800
7		6.528	3.911	7.823
Avg:		4.965	3.786	4.112
Std:		1.734	1.970	2.227
Skewness:		3.350	3.259	3.040
Max:		13.692	13.690	14.667
Min:		3.489	1.956	1.956
Range:		10.203	11.734	12.712

Defect Detection by Slope

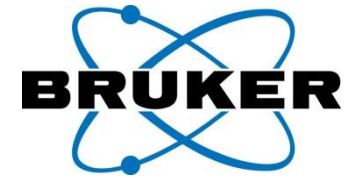
Illustration of throughput



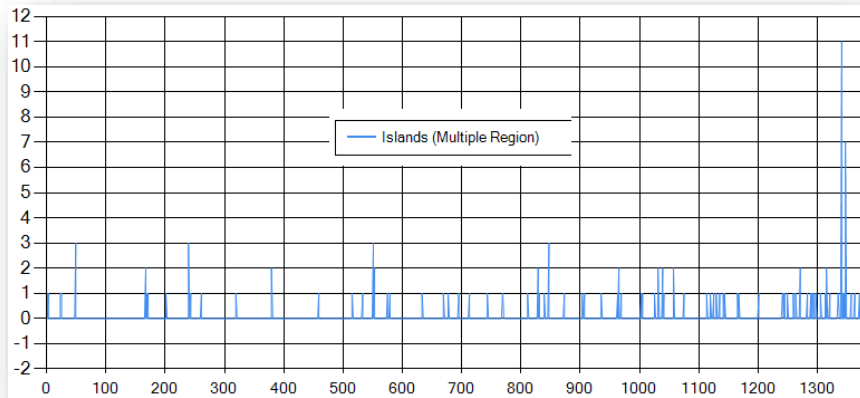
View Video

Defect Detection

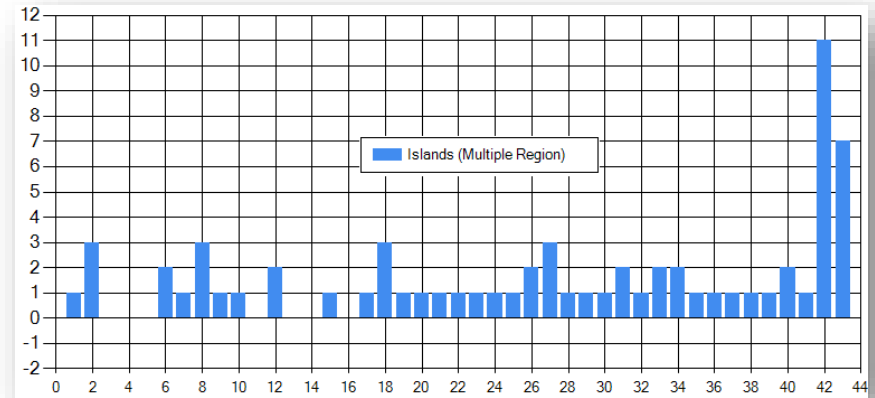
Live monitoring



Number of peaks detected versus location



Maximum number of peaks detected for each row

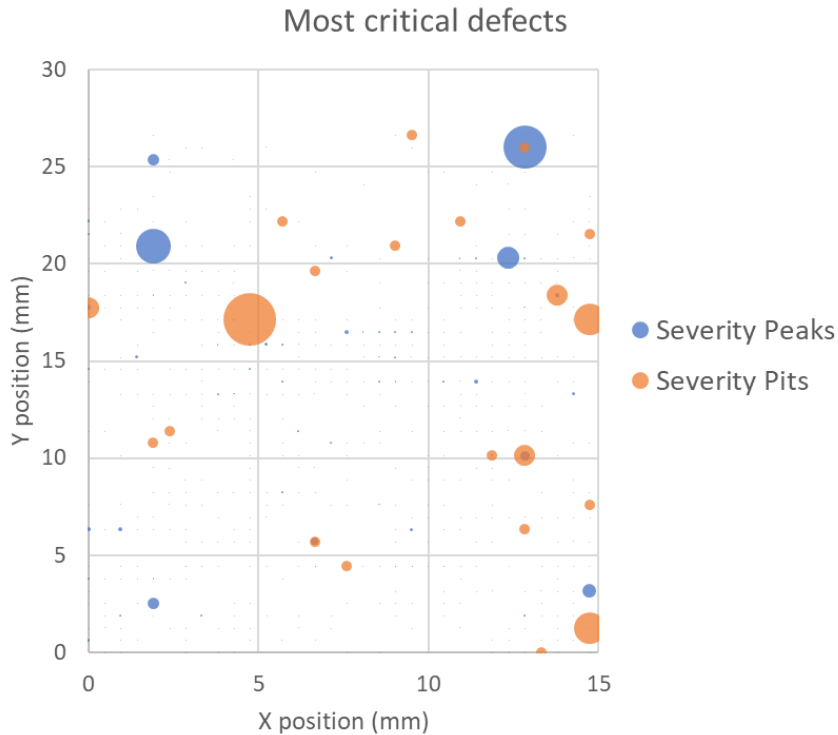
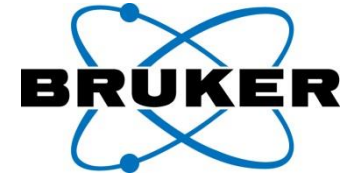


Live statistic for all parameters

Database													
Measurement Number	Time	Row	Column	Islands	Max A Diameter µm	Max Rp% µm	Max X Diameter µm	Max Y Diameter µm	Islands	Max A Diameter µm	Max Rv% nm	Max X Diameter µm	Max Y Diameter µm
	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always	R: N/A M: N/A Always Always
Avg:		22.000	16.500	0.087	9.775	0.674	12.86	11.07	0.036	11.275	-501.7	12.516	11.172
Std:		12.410	9.233	0.471	8.239	0.516	23.43	18.06	0.224	8.574	439.6	10.772	9.625
Max:		43.000	32.000	11.000	56.217	2.456	185.79	156.45	3.000	42.203	-119.5	46.936	45.958
Min:		1.000	1.000	0.000	3.489	0.108	1.96	1.96	0.000	3.659	-2521.1	1.956	2.933
Range:		42.000	31.000	11.000	52.728	2.348	183.83	154.50	3.000	38.543	2401.6	44.980	43.024

Defect Mapping

Display of critical defects

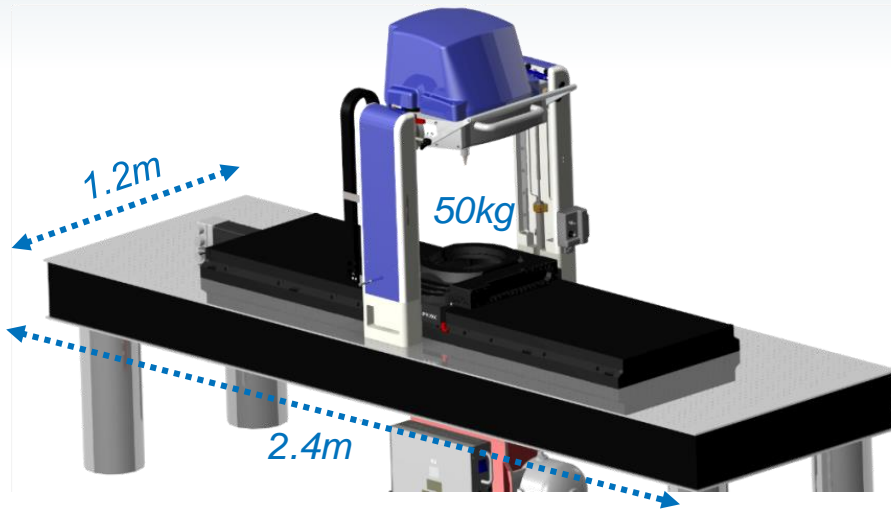
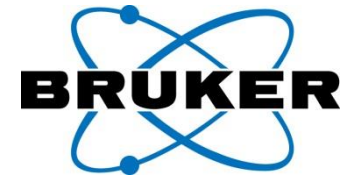


- Severity factor can be worked out from multiple parameters:
 - Number of defects
 - Maximum length of defect
 - Maximum depth/height of defect
- User can place weight on each of those parameters to work out final ranking of severity
- Sphere width represents here the value of severity, providing visual comprehensive map of main defects
- Operator can easily judge if defects are located in too sensitive a region

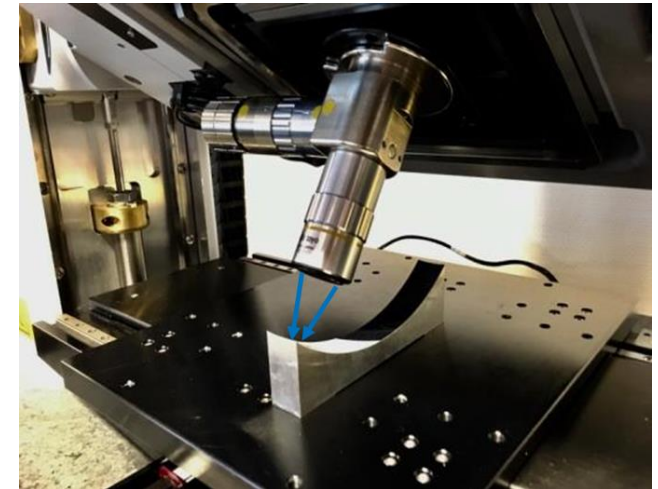
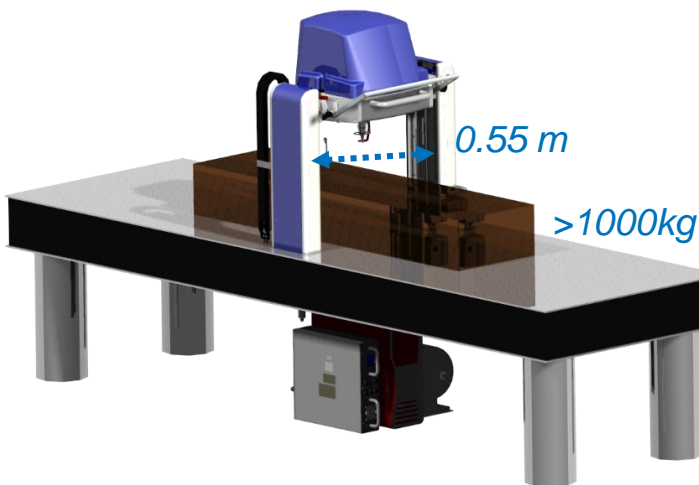
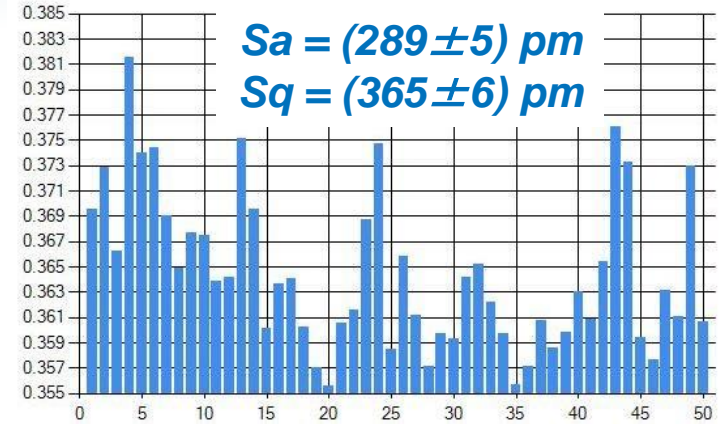
3. Solution for large and aspheric optics

Large and Aspheric Optics

Unique solution



Roughness repeatability – 1X objective

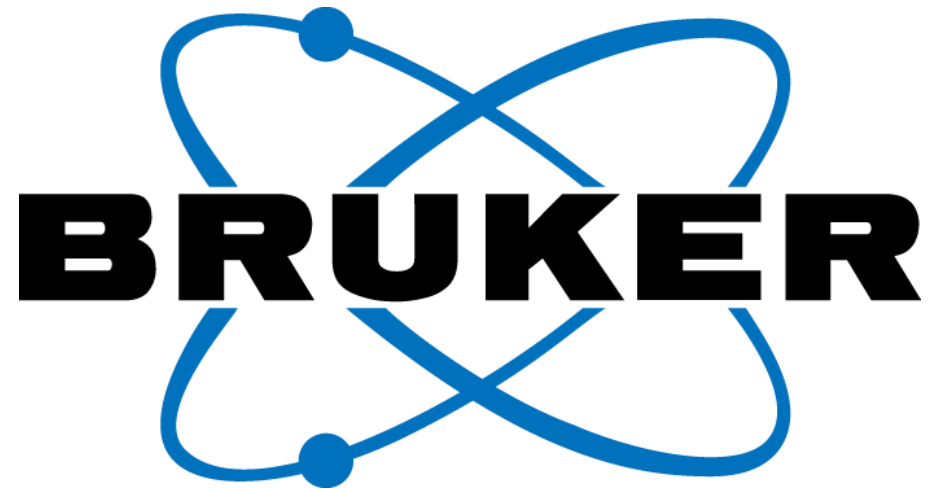


Courtesy of TNO, Delft

Conclusion



- Non-contact interferometric profiler has shown full capability to:
 - Spot defect in effective way
 - Fully characterize each defect
- Main reasons for reliable defect review:
 - Robust measurement modes
 - Complete software automation suite
- Defect review extends to large and aspheric optics with large frame
- Extra discussion needed? Contact Samuel.Lesko@bruker.com



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